

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10/671,922  
Filing Date ..... September 24, 2003  
Inventor ..... Garo J. Derderian et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit.... 2812  
Examiner ..... Gurley, Lynne Ann  
Attorney's Docket No. .... MI22-2296  
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over  
Semiconductor Substrates

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

The attached Form PTO/SB/08a is submitted in compliance with 37 C.F.R. §§ 1.56. Pursuant to Federal Register Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art references, if any, are attached. No admission is made regarding whether all the submitted references are prior art. Citation of these references is respectfully requested.

This Supplemental Information Disclosure Statement is being filed after the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: January 25, 2007

By:

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